

Amendments to the Specification:

Please replace the title as follows:

~~PYROTECHNIC MICROSYSTEM AND METHOD FOR MAKING SAME~~
PYROTECHNIC MICROSYSTEM AND METHOD FOR FABRICATING A
MICROSYSTEM

Please replace the paragraph beginning on page 15, line 26, with the following rewritten paragraph:

The pyrotechnic substance deposit made only in the main combustion chamber 720 (721, ~~Figure 1~~Figure 2) or made as a complete layer (721', ~~Figure 2~~Figure 3 or 13, Figure 4) may be produced with a thickness of less than 100 μm . The thickness of the deposit 721, 721', 13 must be sufficiently small in order to prevent the combustion from propagating beyond a limited zone lying around the initiation zone. However, this thickness of the deposit 721, 721', 13 must be sufficient to generate the gas quantity necessary for obtaining the desired effect. The gas quantity generated furthermore depends in particular on the energetic power of the pyrotechnic material being used, as well as on the geometry of the initiation device. The gas quantity released is therefore controlled by adjusting the thickness of the pyrotechnic substance deposit, the nature of the pyrotechnic material being used as well as the geometry of the initiation device. The greater the energetic power of the material is, the more the deposit thickness can be reduced. It is moreover possible to initiate a greater or lesser surface of the pyrotechnic substance deposit depending on the geometry of the initiation device, which makes it possible to generate more or less gas.